

EGT3  
ENGINEERING TRIPOS PART IIB

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Friday 1 May 2015      2 to 3.30

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**Module 4B6**

**SOLID STATE DEVICES AND CHEMICAL/BIOLOGICAL SENSORS**

*Answer not more than **three** questions.*

*All questions carry the same number of marks.*

*The **approximate** percentage of marks allocated to each part of a question is indicated in the right margin.*

*Write your candidate number **not** your name on the cover sheet.*

**STATIONERY REQUIREMENTS**

Single-sided script paper

**SPECIAL REQUIREMENTS TO BE SUPPLIED FOR THIS EXAM**

CUED approved calculator allowed

Engineering Data Book

Attachment: 4B6 formulae and constants sheet (1 page)

**10 minutes reading time is allowed for this paper.**

**You may not start to read the questions printed on the subsequent pages of this question paper until instructed to do so.**

- 1 (a) Figure 1 shows the double layer sheet capacitance of mercury in contact with NaF solution as a function of ionic strength. Explain the origin of electrical double layer capacitance and give examples using the model used to describe it. [25%]

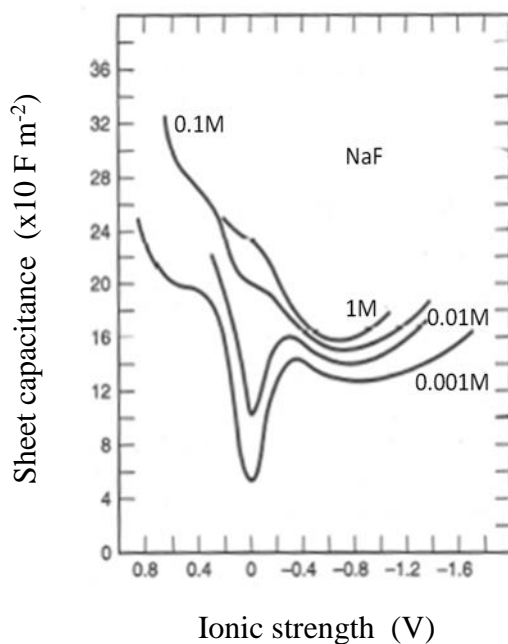


Fig. 1

- (b) (i) Ion Sensitive Field Effect Transistor (ISFET) is used as a pH sensor by measuring the change in the double layer potential  $\psi_L$ . With reference to the acidic/basic reactions at the surface in Fig. 2, write down the equations for the equilibrium constant  $K_b$  and  $K_a$ .  $H_s^+$  is the  $H^+$  at the surface in the solution side. [15%]

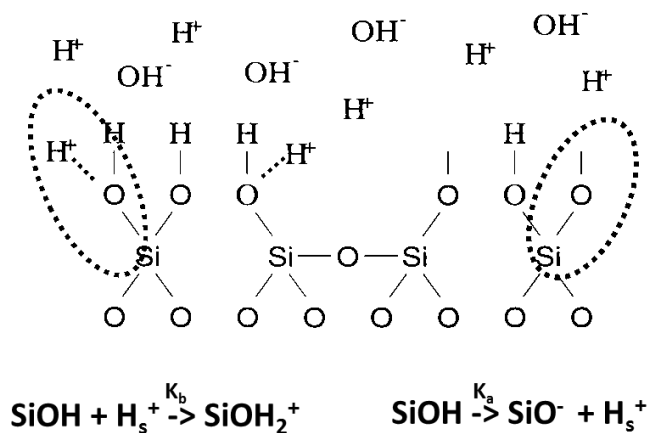


Fig. 2

(ii) Express the concentration of  $H_s^+$  at the surface in terms of  $K_b$ ,  $K_a$ , the concentrations of  $SiOH_2^+$  and  $SiO^-$ . [25%]

(iii) With the Boltzmann relationship shown below, express the double layer potential  $\psi_L$  in terms of  $K_b$ ,  $K_a$  and concentration of hydrogen ions in the bulk solution,  $H_b^+$ . [35%]

$$[H_s^+] = [H_b^+] \exp\left(-\frac{q\psi_L}{kT}\right)$$

State all assumptions and approximations made.

2 (a) For the ferroelectric thin film material shown in Fig. 3, find the values of:

(i) Remnant Polarisation. [10%]

(ii) Coercive field. [10%]

(iii) Energy density consumed in a full switching cycle. [10%]

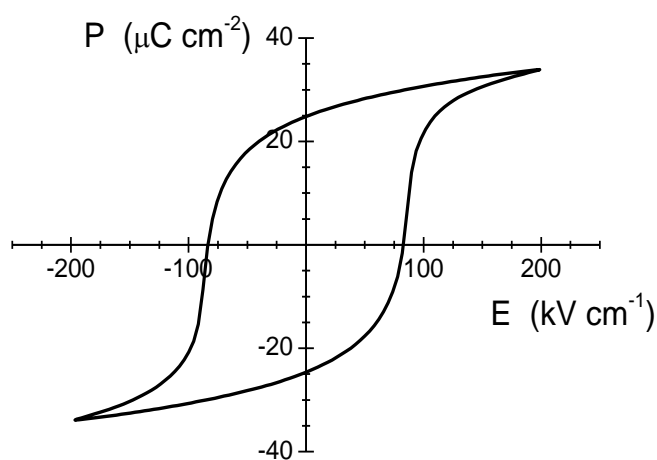


Fig. 3

(b) A ferroelectric thin film capacitor in a Ferroelectric Random Access Memory (FRAM) cell is made of the ferroelectric material shown in Fig. 3 with dimensions of 150 nm in thickness and  $0.18 \mu\text{m}$  by  $0.18 \mu\text{m}$  square in size.

(i) If we apply a voltage across it in the form of a positive step function with a height of +3V, what will be the switching charge if the initial information stored in this memory cell was of State '1' (positively polarised) or State '0' (negative polarised), respectively? [20%]

(ii) If the bit line parasitic capacitance, which is utilised as a sensing capacitor, is 2 pF, what are the sensed voltage levels for State '1' and State '0', respectively? [20%]

(iii) Theoretically, how small in size can this ferroelectric capacitor be in order to maintain its original function as a memory cell, given that the Read-out sense amplifier has a resolution of 1 mV? [10%]

(c) Figure 4 shows the results of an accelerated reliability test for the above memory cell. What are the projected life times of this device at 80 °C and 30 °C, respectively? (Hint: assume  $t_{\text{failure}} \sim \exp(+\Delta E/kT)$ , where  $\Delta E$  is a constant and  $k$  the Boltzmann constant.) [20%]

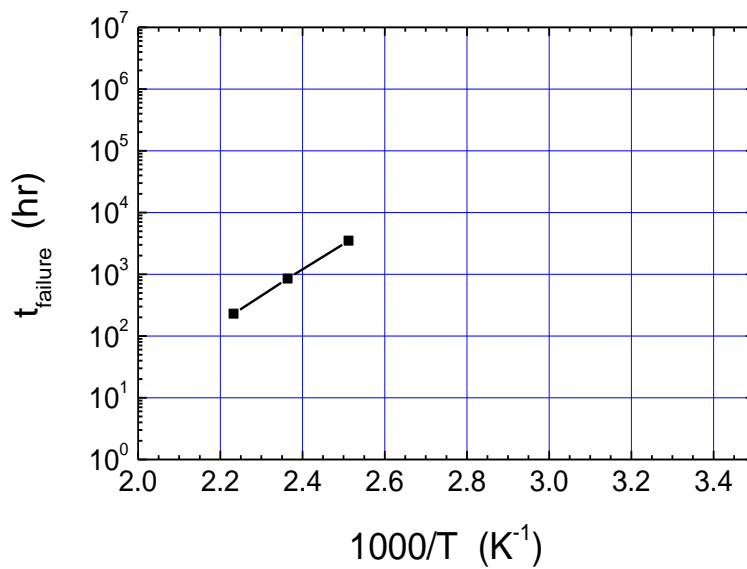


Fig. 4

State all assumptions and approximations made.

3 (a) Explain:

- (i) How a Magnetic Tunnel Junction (MTJ) works in the Current-Perpendicular-to-Plane (CPP) and Current-In-Plane (CIP) configurations, as shown in Fig. 5. [20%]
- (ii) Whether the lower Co layer, which is not in contact in the CIP configuration, has any impact on the measured current and why. [20%]
- (iii) How a bit of information is stored and which physical quantities are readout. [10%]

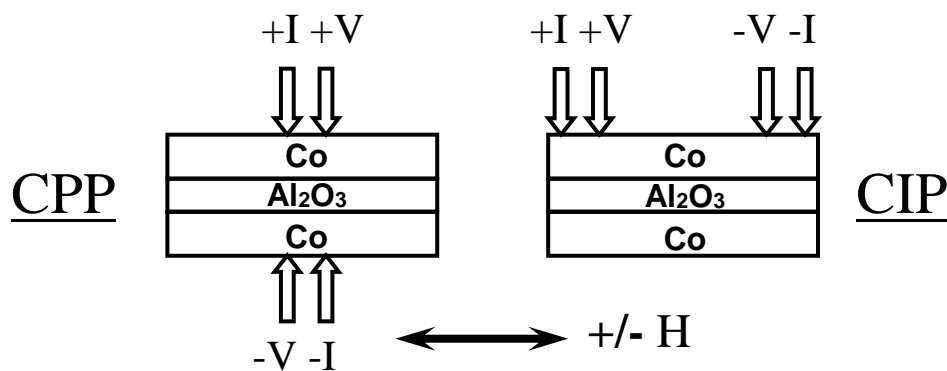


Fig.5

(b) A sketch of a Magnetic Random Access Memory (MRAM) array is shown in Fig. 6(a). For a given cell (say B2-W2), explain without reproducing Fig. 6(a):

- (i) How to write a bit of information into the cell, with reference to Fig. 6(b). [30%]
- (ii) How to read the stored information. [10%]
- (iii) The importance of the physical geometry of the device. [10%]

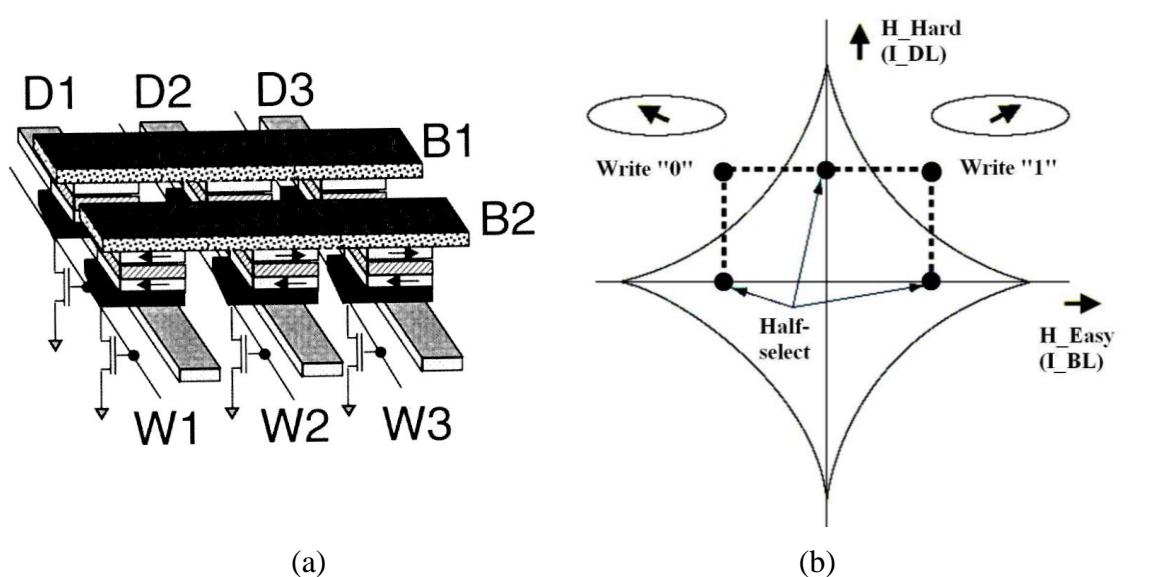


Fig. 6

State all assumptions and approximations made.

4 (a) Define the threshold voltage for a Metal-Oxide-Semiconductor (MOS) capacitor. [10%]

(b) An ideal p-type silicon MOS capacitor has the following parameters:

oxide thickness	$d = 2.0 \times 10^{-7} \text{ m}$
oxide dielectric constant	$\epsilon_i = 3.9 \epsilon_0$
semiconductor dielectric constant	$\epsilon_s = 11.9 \epsilon_0$
intrinsic carrier concentration	$n_i = 1.45 \times 10^{16} \text{ m}^{-3}$
acceptor concentration	$N_A = 2.0 \times 10^{21} \text{ m}^{-3}$
effective Density of States in Conduction Band	$N_C = 2.08 \times 10^{25} \text{ m}^{-3}$
effective Density of States in Valence Band	$N_V = 1.04 \times 10^{25} \text{ m}^{-3}$

Calculate the threshold voltage of this device at room temperature. [30%]

(c) A MOS capacitor with the above parameters contains interface states at the silicon/SiO<sub>2</sub> interface. These states are acceptor-like, that is each state carries a charge  $q = -1.6 \times 10^{-19} \text{ C}$  when occupied, and are neutral when empty. Their density,  $D_{it}$ , is constant throughout the bandgap:  $D_{it} = 10^{16} \text{ m}^{-2} \text{ eV}^{-1}$ .

Assume that the Fermi function  $F(E)$  can be approximated as a step function:

$$F(E) = 1 \quad \text{for } E \leq E_F$$
$$F(E) = 0 \quad \text{for } E > E_F.$$

Calculate the threshold voltage at room temperature in this case. [30%]

(d) Discuss whether the result of the calculation in (c) would change, if the correct Fermi function is employed:

(i) For the  $D_{it}$  above.

(ii) For any  $D_{it}$ . [30%]

State all assumptions and approximations made.

**END OF PAPER**



Version DPC/4 + List of Answers

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ENGINEERING TRIPOS PART IIB

Module 4B6

SOLID STATE DEVICES AND CHEMICAL/BIOLOGICAL SENSORS

### **Formulae and constants**

$\epsilon_0 = 8.85 \times 10^{-12}$  Farad  $\text{m}^{-1}$       permittivity in vacuum

$k = 1.38 \times 10^{-23}$  Joules  $\text{K}^{-1}$       Boltzmann's constant

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ENGINEERING TRIPOS PART IIB

Module 4B6

SOLID STATE DEVICES AND CHEMICAL/BIOLOGICAL SENSORS

**List of Answers**

1. (b) (i)

$$K_b = \frac{[\text{SiOH}_2^+]}{[\text{H}_s^+][\text{SiOH}]} \quad K_a = \frac{[\text{H}_s^+][\text{SiO}^-]}{[\text{SiOH}]}$$

(ii)

$$\frac{K_a}{K_b} = \frac{[\text{H}_s^+]^2 [\text{SiO}^-]}{[\text{SiOH}_2^+]} \quad \therefore [\text{H}_s^+] = \sqrt{\frac{K_a [\text{SiOH}_2^+]}{K_b [\text{SiO}^-]}}$$

(iii)

$$-\ln [\text{H}_b^+] + \ln \left( \frac{K_a}{K_b} \right)^{\frac{1}{2}} = -\frac{q \psi_L}{kT} + \ln \left( \frac{[\text{SiO}^-]}{[\text{SiOH}_2^+]} \right)^{\frac{1}{2}}$$

$$-\ln [\text{H}_b^+] + \ln \left( \frac{K_a}{K_b} \right)^{\frac{1}{2}} \approx -\frac{q \psi_L}{kT} \quad \underbrace{\ln \left( \frac{[\text{SiO}^-]}{[\text{SiOH}_2^+]} \right)^{\frac{1}{2}}}_{\text{negligible}}$$

2. (a) (i) 25 μC cm<sup>-2</sup>; (ii) 80 kV cm<sup>-1</sup>; (iii) 8x10<sup>6</sup> J m<sup>-3</sup>

(b) (i) 2.9 fC for '1', 19 fC for '2'; (ii) 1.5 mV for '1', 9.5 mV for '0';

(iii) 58 nm x 58 nm

(c) ~10 yrs at 80°C, ~1,000 yrs at 30°C

3.

4. (b) 1.79 V; (c) 9.99 V